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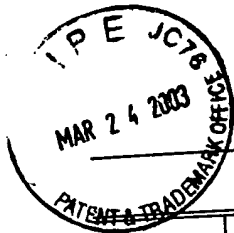
APPLICANT
SUGAYA et al.

FILING DATE
21 February 2003

GROUP
2881

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use several sheets if necessary)



U.S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
5A		L.A. Giannuzzi <i>et al.</i> , "Focused ion beam milling and micromanipulation lift-out for site specific cross-section TEM specimen preparation," <i>Mat. Res. Soc. Symp. Proc.</i> , Vol. 480, pp. 19-27, <u>Materials Research Society</u> , 1997.

EXAMINER

DATE CONSIDERED

April 8 2003

EXAMINER: Initial if citation is considered, draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

(Form PTO-1449 [6-4])

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